

## **New monoflange design also prevents fugitive emissions**

**Klingenberg, May 2019**

**Compact design and minimised leakage potential: The new WIKA model IVM monoflange for connecting pressure measuring instruments to the process is particularly suitable for applications involving critical liquids, gases and vapours. Special seals also prevent fugitive emissions in accordance with TA-Luft (VDI 2440) and ISO 15848-1.**

The monoflange is manufactured and tested to comply with various common standards such as ASME BPVC. It is designed for a long service life, even under difficult conditions. The valves work durably, smoothly and precisely, even at high pressures. The metal seat of the non-rotating spindle tip is tested for bubble tightness. To avoid seizure and leaks, the threaded mounting of the bonnets is not in contact with the medium.

In a version with OS&Y bonnet, firesafe tested to API 607 and ISO 10497/BS 6755-2, the IVM can also be mounted directly to the process without additional first isolation.

For the combination of the monoflange (or other protective devices) with a pressure measuring instrument, WIKA offers professional assembly. Customers receive an application-specific, complete solution ("hook-up"), ready for installation and leak-tested.

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**WIKA company photograph:**  
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press release

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